

Form PTO-1449 (REV. 1/06) <b>INFORMATION DISCLOSURE STATEMENT</b> (Use several sheets if necessary)			US Dept. of Commerce PATENT & TRADEMARK OFFICE	ATTY DOCKET NO. 128180	APPLICATION NO. 10/1582344 National PCT/FR2004/003203	
			<b>APPLICANT</b> Elisabeth DELEVOYE			
			<b>FILING DATE</b> June 9, 2006		2856	
<b>U.S. PATENT DOCUMENTS</b>						
Examiner Initials	Cite No.	Document Number	Date	Name		
<b>FOREIGN PATENT DOCUMENTS</b>						
Examiner Initials	Cite No.	Document Number	Date	Country	With English Abstract	With English Translation
X	1.	EP 0 904 522 A	03/31/1999	EUROPE		
X	2.	WO 02/057728 A	07/25/2002	WIPO		
X	3.	EP 1 126 242 A	08/22/2001	EUROPE		
<b>OTHER DOCUMENTS</b>						
Examiner Initials	Cite No.	(Including Author, Title, Date, Pertinent Pages, etc.)				
X	4.	MAENAKA et al.; "A study of silicon angular rate sensors using anisotropic etching technology"; <i>Sensors and Actuators</i> ; Vol. A43; No. 1/3; May 1, 1994; pgs. 72-77.				
<b>EXAMINER</b>				<b>DATE CONSIDERED</b>		
John Chapman				10/3/07		
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.						